



PATENT
ATTORNEY DOCKET NO. 07977/052001/US3053

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Hisashi Ohtani et al. Art Unit: 1765
Serial No.: 08/690,747 Examiner: R. Kunemund
Filed : August 1, 1996
Title : METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

Box AF
Assistant Commissioner for Patents
Washington, DC 20231

AMENDMENT

Sir:

In response to the Official Action dated April 7, 1999,
paper no. 9 in the above-referenced case, kindly amend the above-
referenced application as follows:

In the Claims

Please amend the claims as follows.

1. (Amended) A method for manufacturing a
semiconductor device comprising the steps of:

forming a non-single crystalline semiconductor film to
become at least a channel forming region on an insulating
surface;

patterning said semiconductor film into a patterned
semiconductor film having peripheral portions;

Date of Deposit October 16, 1999

I hereby certify that this correspondence is being deposited with the
United States Postal Service as first class mail with sufficient postage
on the date indicated above and is addressed to the Assistant
Commissioner for Patents, Washington, D.C. 20231.

Deborah Dean

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